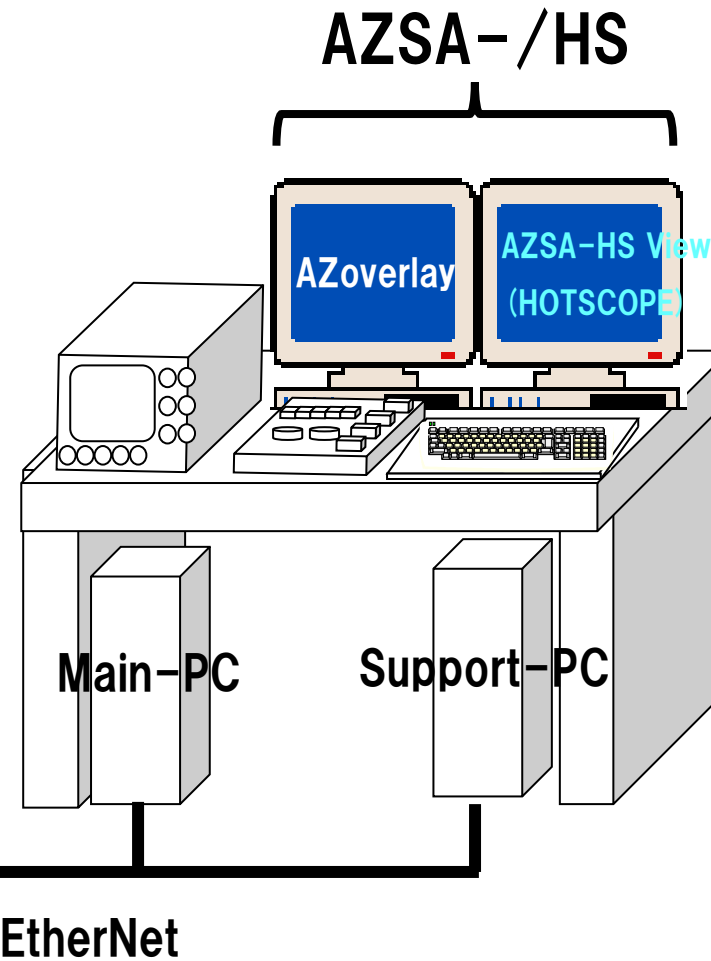


What is AZSA-HS ?

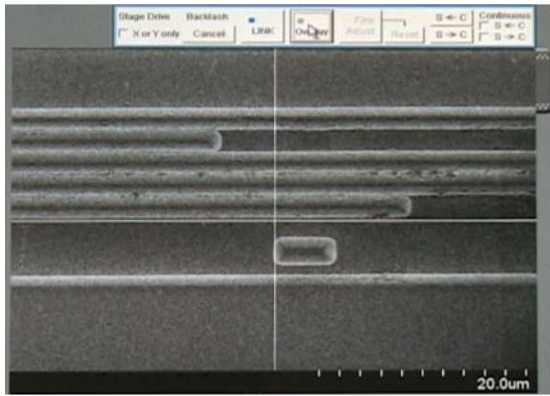
System configuration

**Supported devices
(SEM,FIB,Prober.Emission etc.)**

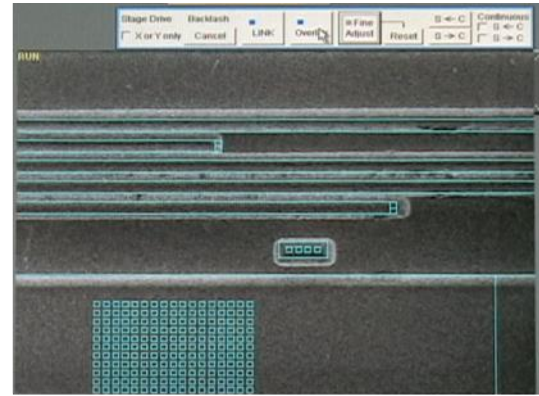


Basic Function : Overlay

- Overlay of SEM / SIM Image and CAD Data
- The circuit under the sample surface can be identified

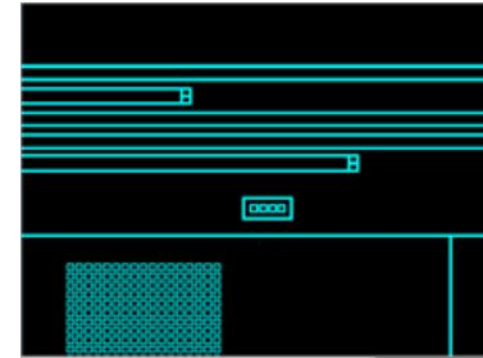


SEM/SIM Image



Overlay

(Display CAD data superimposed
on SEM / SIM image)



CAD Data

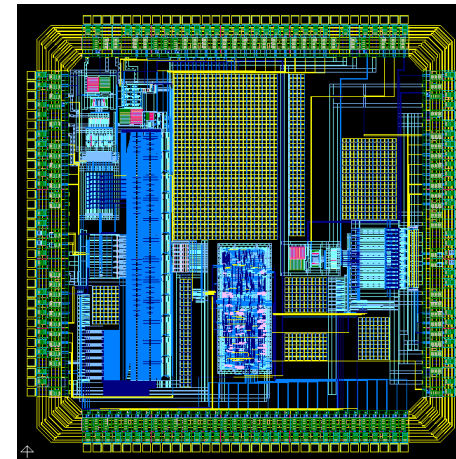
Basic Function : Stage Link

- When the CAD data position is changed, the SEM / SIM image moves to the same location in synchronization.
- When the display of CAD data is enlarged / reduced, the SEM / SIM image is enlarged / reduced at the same magnification.
- The change from the SEM/SIM image side is also possible.



FIB-SEM-Prober-FIB-SEM

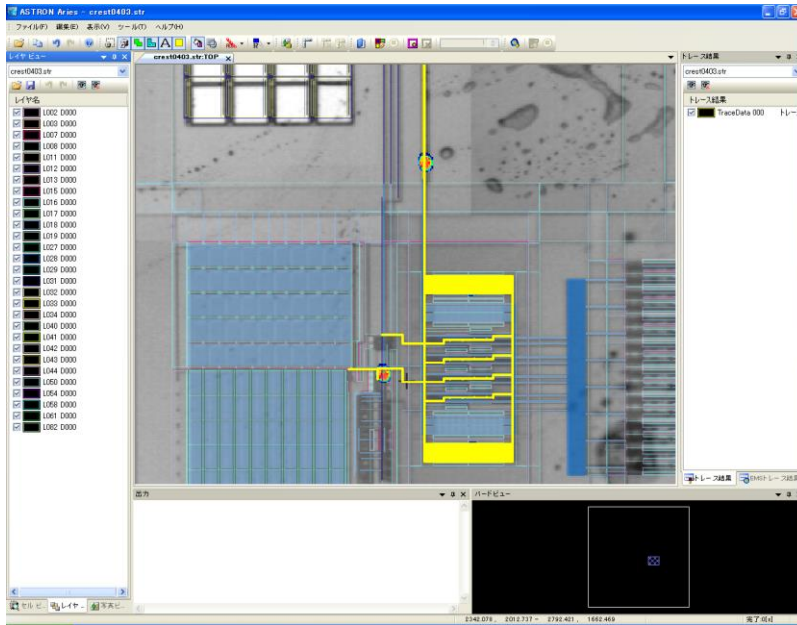
Stage / magnification
Link



CAD Data (Layout Data)

Basic Function : Equipotential node trace

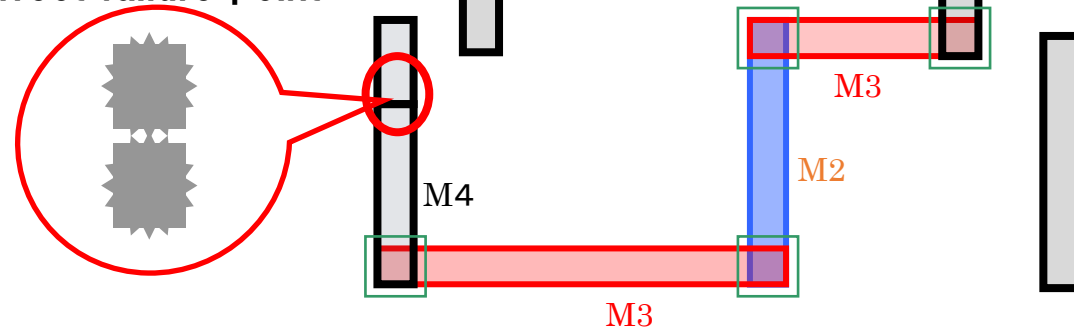
✓ Trace and highlight equipotential nodes (wiring)



When you pick a figure on the layout, all equipotential points are highlighted.

Effective for searching for a fault location.

Correct failure point



Performance Features of **AZSA-HS**

✓ Direct Input of GDS data

✓ Simple Alignment

→ “Quick Stage function” & “Automatic scale adjustment function”

Coming soon

✓ Wafer Mapping (Option)

→ Based on the defect information imported from various defect inspection devices, the defect position can be displayed on the Wafer Map and the defect-related information can be viewed in a list.

✓ Simple GUI (Editable)

→ AZSA can edit GUI menu only for required functions

✓ Data Locator (Marking)

→ AZSA can specify the position by the processing frame, arbitrarily set the name and save it to the list on the PC screen

New function

→ Defect information taken from the defect inspection device and FIB / SEM processing information are saved in the holder linked to the marking coordinates.

Performance Features of **AZSA-HS**

✓ Large scale response

→Correspondence to large scale data (**100 G <**)

✓ Cross-section & 3D display function

✓ Multi format (Option)

→Add New formats of **OASIS**, MEBES, JEOL, HL, TOSHIBA, Job Deck etc.
in addition to LEF / DEF, GDS

New function

✓ Dummy GDS Operation

→Even if there is no CAD data, the same place observed with an optical microscope
can be easily identified with an electron microscope image.

✓ Schematic generation (Option)

→Schematic generation from layout data
→Cross probe between layout data and generated schematic data
→Easy-to-see schematic display by net / instance display function

Supported Devices



Regulus series



NP6800、NE4000



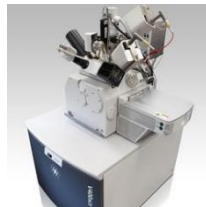
NX series,MI4050

Hitachi High-Tech



Centrios

thermo
scientific



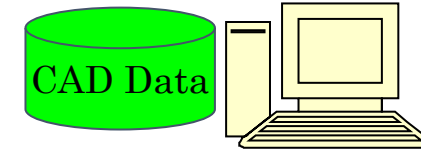
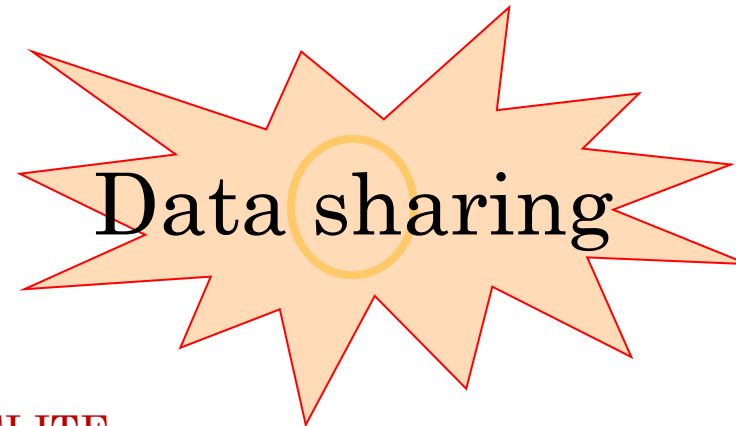
V400ACE



Helios series

Scios

ELITE



CAD Server



HAMAMATSU PHEMOS



JEOL JIB-4000